Bio-inspired Silicon Nanospikes Fabricated by Metal-Assisted Chemical Etching for Anti-bacterial, Wearable Systems

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Abstract— Researchers have recently discovered that the nano-structures found on cicada wings can mechanically kill bacteria upon contact. Reported here is a simple, fast, low-cost, and scalable nanofabrication method based on metal-assisted chemical etching using a single crystal silicon substrate, to create biological inspired anti-bacterial surfaces. We evaluated the effect of etch time, the anti-bacterial surface coverage, and speed of incubation on bacterial growth rate. We discovered that a 6 minute etch time, an anti-bacterial surface coverage greater than 0.5 cm^2 , and a static incubation environment generated the greatest rate of reduction in bacterial growth over time, and lysed all bacteria in 3 hours. These findings suggest these nano-spikes may be a useful anti-bacterial surface for use in wearable systems.

I. INTRODUCTION

Antibacterial surfaces can limit bacterial growth and inhibit infection, and are useful in wearable devices such as contact lens and medical implants [1]. To fabricate biomimetic nano-structures similar to cicada wings, researchers have relied on non-lithographic methods such as reactive ion etching and glancing angle deposition, which are expensive and require a vacuum environment. Here, we proposed to create nano-spikes using a low-cost metal-assisted chemical etching method (MacEtch) that uses two common chemicals: hydrofluoric acid and silver nitrate to etch a single crystal silicon in minutes at room temperature [2].

II. MAIN RESULTS

To determine if the rapid MacEtch method can generate the optimal pitch of 200 nm that has been reported to be critical in the bactericidal property [3], silicon nano-spike samples were prepared at 2.5, 6, and 10 minute etch times and their anti-bactericidal activity evaluated (data not shown). We found that at 6 minutes, the height of the nano-spikes is ~1.1 μ m, with an average pitch of 220 nm (Figure 1 (a) and (b)). Figure 1 (c) shows a helium ion microscope image of a lysed *E. coli* bacterium on a 6 minute etched nano-spike sample.

We evaluated the effect of surface area and speed of incubation on bacterial growth rate. We discovered that the a nano-spike coverage larger than 0.5 cm² can lyse all bacteria in 3 hours at a starting $OD_{600} = 0.1$ (Figure 2 (a)). Interestingly, a nano-spiked sample incubated in a static environment is more effective at reducing bacterial growth compared to a same sized sample rotated at 100 rpm (Figure 2 (b)). We

hypothesize a sample in a static condition would allow more time for *E. coli* to attach to the surface and get lysed by the nano-spiked surface. In contrast, in a rotation condition, it is more difficult for the bacterium to attach to the surface, and therefore less likely to get lysed.

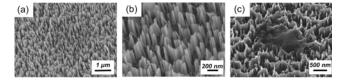


Figure 1. SEM images of silicon nanospikes formed by MacEtch at 6 minutes at (a) 1 μ m and (b) 200 nm resolution. (c) Helium Ion Microscope image of a lysed *E.coli* bacterium on a nano-spiked surface.

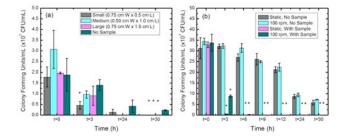


Figure 2. *E. Coli* bacterial colony growth at different time points as a function of (a) different MacEtch surface coverage, and (b) in a static or rotational environment. Error bars are s.d values of triplicate plates. Statistical significance was determined by a one-tailed t-test against control.

III. CONCLUSIONS

We presented a novel, low-cost, and scalable MacEtch method for creating anti-bacterial surfaces useful for wearable and medical sensor applications. Using the MacEtch method, we demonstrated that a 6 minute etch time, with an anti-bacterial surface greater than 0.5 cm², in a static environment is most successful at eliminating bacterial growth in 3 hours, with a starting $OD_{600} = 0.1$.

References

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